NOV 3 0 2000 WE IN T

N THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of

Oinghong K. Gao et al.

Application No.: 10/600,273

Filed: June 20, 2003

MULTIPLE ZONE GAS

DISTRIBUTION APPARATUS FOR

THERMAL CONTROL OF

SEMICONDUCTOR WAFER.

MAIL STOP AF

Group Art Unit: 1763

Examiner: Rakesh Kumar Dhingra

Confirmation No.: 6096

AMENDMENT AFTER FINAL REJECTION

Commissioner for Patents

P.O. Box 1450

Alexandria, VA 22313-1450

Sir:

In reply to the Office Action dated October 4, 2005, please amend the aboveidentified patent application as follows:

2/01/2005 SZENDIE1 00000063 10600273

1 FC:1202

300.00 OF